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## \*BIBDATASHEET\*

CONFIRMATION NO. 2494

Bib Data Sheet

SERIAL NUMBER 09/913,334	FILING DATE 08/13/2001  RULE	CLASS 438	GROUP ART UNIT 2823	ATTORNEY DOCKET NO. 110386
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## APPLICANTS

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## \*\* CONTINUING DATA \*\*\*\*\*

This application is a 371 of PCT/JP00/09185 12/25/2000  
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## \*\* FOREIGN APPLICATIONS \*\*\*\*\*

JAPAN 11-374052 12/28/1999  
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Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR	SHEETS	TOTAL	INDEPENDENT
35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance	COUNTRY	DRAWING	CLAIMS	CLAIMS
Verified and Acknowledged Examiner's Signature <u>FOURSON</u> Initials <u>G</u>	JAPAN	2	22	7

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## TITLE

Etchant, etching method and semiconductor silicon wafer  
FOR WAFER  
A A

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